

# microDICE™

## TLS-Dicing™ System for Separation of SiC Wafers

3D-Micromac's high-performance microDICE™ laser dicing system separates wafers into dies using TLS-Dicing™ technology (Thermal-Laser-Separation).

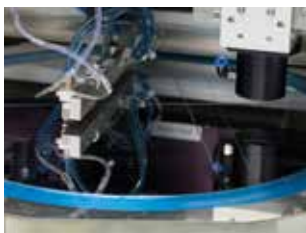
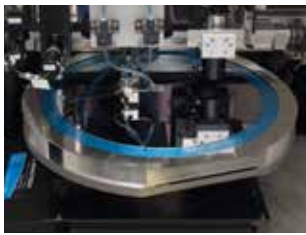
microDICE™ significantly reduces the dicing cost per wafer. Cleaving with microDICE™ provides outstanding edge quality while increasing the yield and the throughput, especially for SiC.

microDICE™ offers:

- Significant higher throughput due to dicing speed up to 300 mm/s
- Minimal cost of ownership
- More dies per wafer by reduced street width



# microDICE™ - System Configuration



The microDICE™ standard system configuration consists of:

- Cleaving function
- Soft scribe function
- Micro stretching function

Available options:

- Automated wafer handling
- Second unit for scribing
- SECS/GEM interface
- Filter fan unit
- Drying unit

Wafer size	<ul style="list-style-type: none"> <li>▪ Up to 300 mm (12") wafer size</li> </ul>
Laser sources	<ul style="list-style-type: none"> <li>▪ Two integrated long lifetime, low maintenance fiber laser sources</li> <li>▪ One fiber laser source for cleaving process</li> <li>▪ One fiber laser source for soft scribing process</li> </ul>
Positioning system	<ul style="list-style-type: none"> <li>▪ Direct driven XY-gantry system</li> <li>▪ Rotation axis with vacuum chuck</li> <li>▪ Z positioning system for laser optics and cameras</li> <li>▪ Position accuracy X axis: ± 0.0018 mm, repeatability: ± 0.00075 mm</li> <li>▪ Position accuracy Y axis: ± 0.001 mm, repeatability: ± 0.0004 mm</li> </ul>
Wafer chuck	<ul style="list-style-type: none"> <li>▪ Vacuum chuck up to 300 mm wafer size (tape and frame)</li> <li>▪ Integrated patented micro stretching function for edge protection</li> </ul>
Software microMMI	<ul style="list-style-type: none"> <li>▪ Control of all components and parameters</li> <li>▪ Different user levels supported (administrator, supervisor, operator)</li> </ul>
Standards	<ul style="list-style-type: none"> <li>▪ Compatible with common SEMI standards</li> <li>▪ Laser safety class 1</li> <li>▪ Clean room class 6</li> </ul>
Consumables	<ul style="list-style-type: none"> <li>▪ Cooling water, compressed air, electrical power</li> <li>▪ Only 600 ml DI-water for 1 h active dicing time</li> </ul>
Machine dimensions	<ul style="list-style-type: none"> <li>▪ 2005 x 2000 x 2090 mm<sup>3</sup> (W x H x D) incl. automatic handling</li> </ul>

Changes in accordance to technical progress are reserved.